

Title (en)
METHOD FOR MANUFACTURING AN OPTOELECTRONIC SENSOR

Title (de)
VERFAHREN ZUR HERSTELLUNG EINES OPTOELEKTRONISCHEN SENSORS

Title (fr)
PROCÉDÉ DE FABRICATION D'UN CAPTEUR OPTOÉLECTRONIQUE

Publication
EP 3432023 B1 20190814 (DE)

Application
EP 18180276 A 20180628

Priority
DE 102017116492 A 20170721

Abstract (en)
[origin: US2019022948A1] A method of manufacturing an optoelectronic sensor (10) is provided that has a reception unit (22) having a reception optics (24), a light receiver (28), and a diaphragm (26) therebetween, wherein the diaphragm (26) is arranged in a focal plane of the reception optics (24) so that a received light beam (20) generated by the reception optics is incident through the diaphragm aperture (42) of the diaphragm (26) at the point of smallest constriction. The diaphragm (26) is manufactured as an individual diaphragm using the reception optics (24).

IPC 8 full level
G01S 7/481 (2006.01); **G01S 7/497** (2006.01)

CPC (source: EP US)
B29C 64/393 (2017.07 - US); **B33Y 10/00** (2014.12 - US); **B33Y 50/02** (2014.12 - US); **B33Y 80/00** (2014.12 - US);
G01S 7/4816 (2013.01 - EP US); **G01S 7/497** (2013.01 - EP US)

Cited by
EP3939774A1; DE202020101894U1; DE102020109596A1; DE102020109596B4; DE102020118941A1

Designated contracting state (EPC)
AL AT BE BG CH CY CZ DE DK EE ES FI FR GB GR HR HU IE IS IT LI LT LU LV MC MK MT NL NO PL PT RO RS SE SI SK SM TR

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JP 2019053040 A 20190404; JP 6718927 B2 20200708; US 10864679 B2 20201215; US 2019022948 A1 20190124

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EP 18180276 A 20180628; DE 102017116492 A 20170721; JP 2018134355 A 20180717; US 201816035751 A 20180716